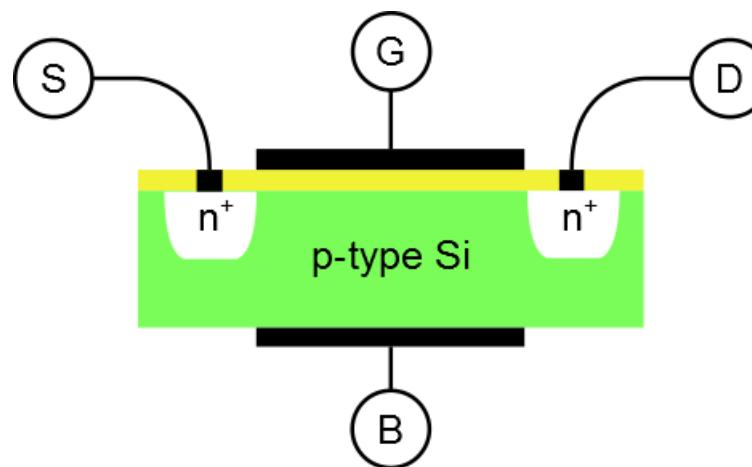




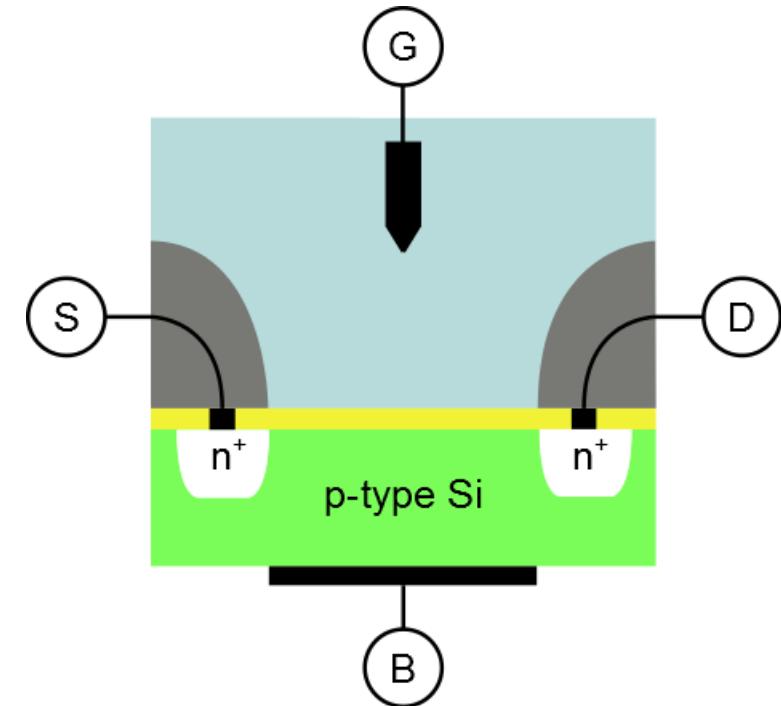
Reducing Electrostatic Screening in Field-Effect-Transistor-Based (FET-based) Biosensors

Kaveh Shoorideh and Chi On Chui
Annual Research Review
UCLA
12/4/2012

Ion Sensitive Field-Effect Transistor (ISFET)

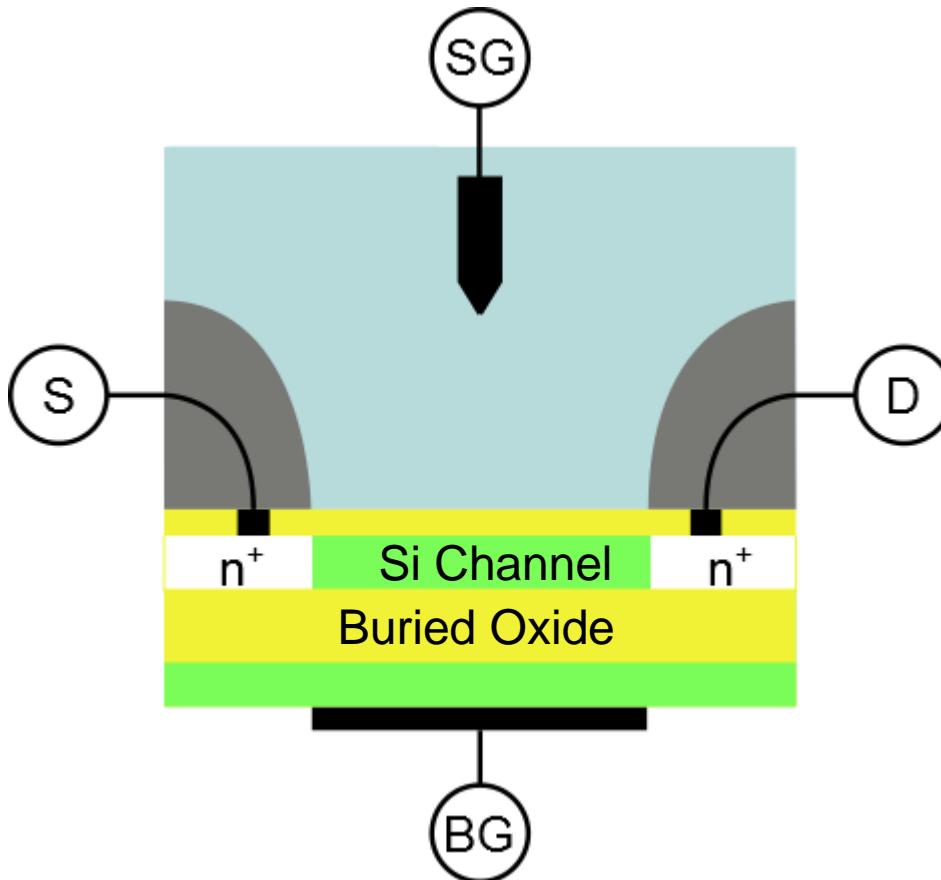


MOSFET

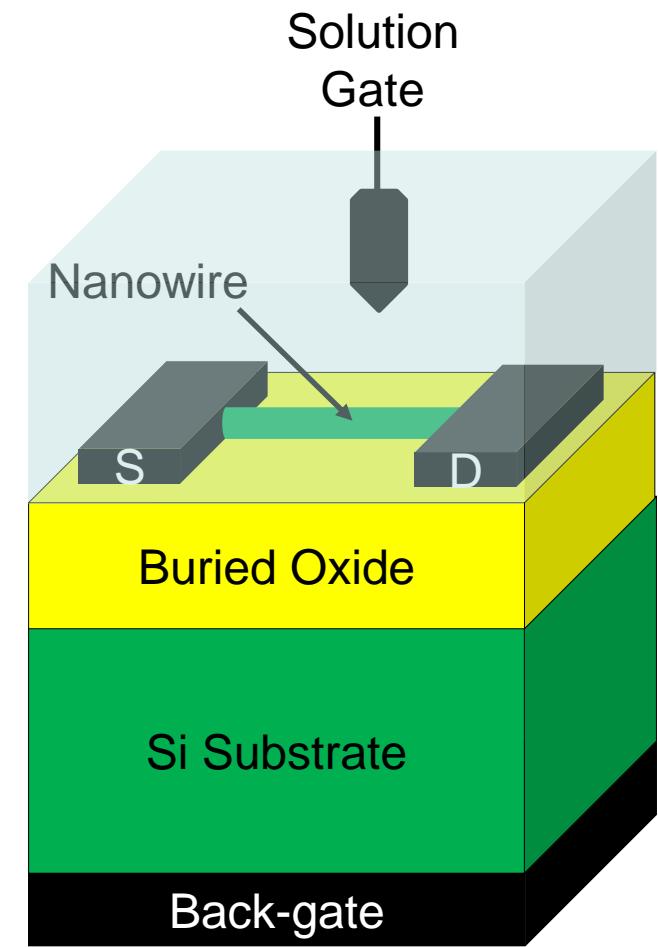


ISFET

Non-Planar Channel FET Biosensors

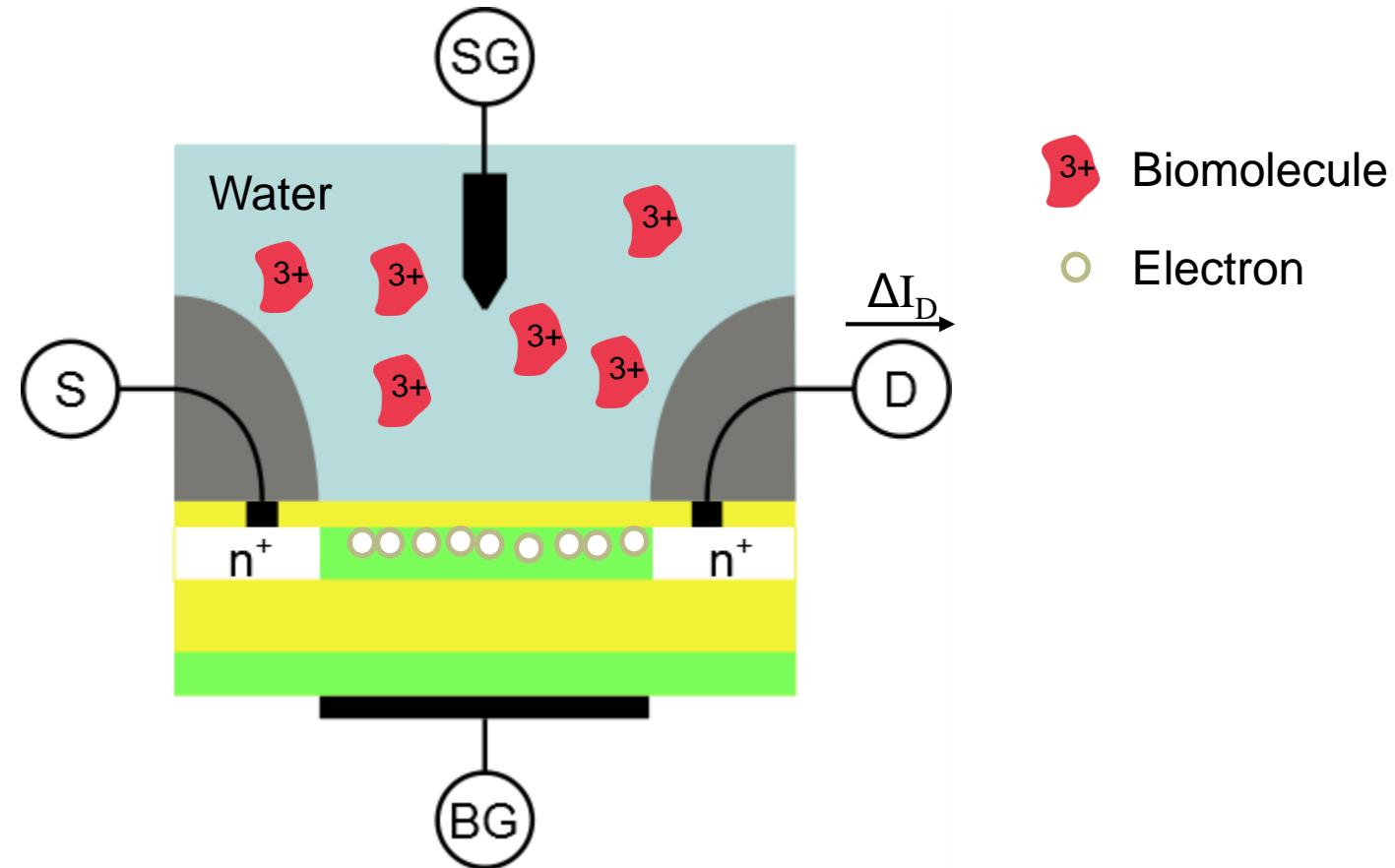


**Silicon-on-Insulator
Biosensors**



**Nanowire
Biosensors**

Biosensor Operation in Water



Biosensor Operation in Electrolyte

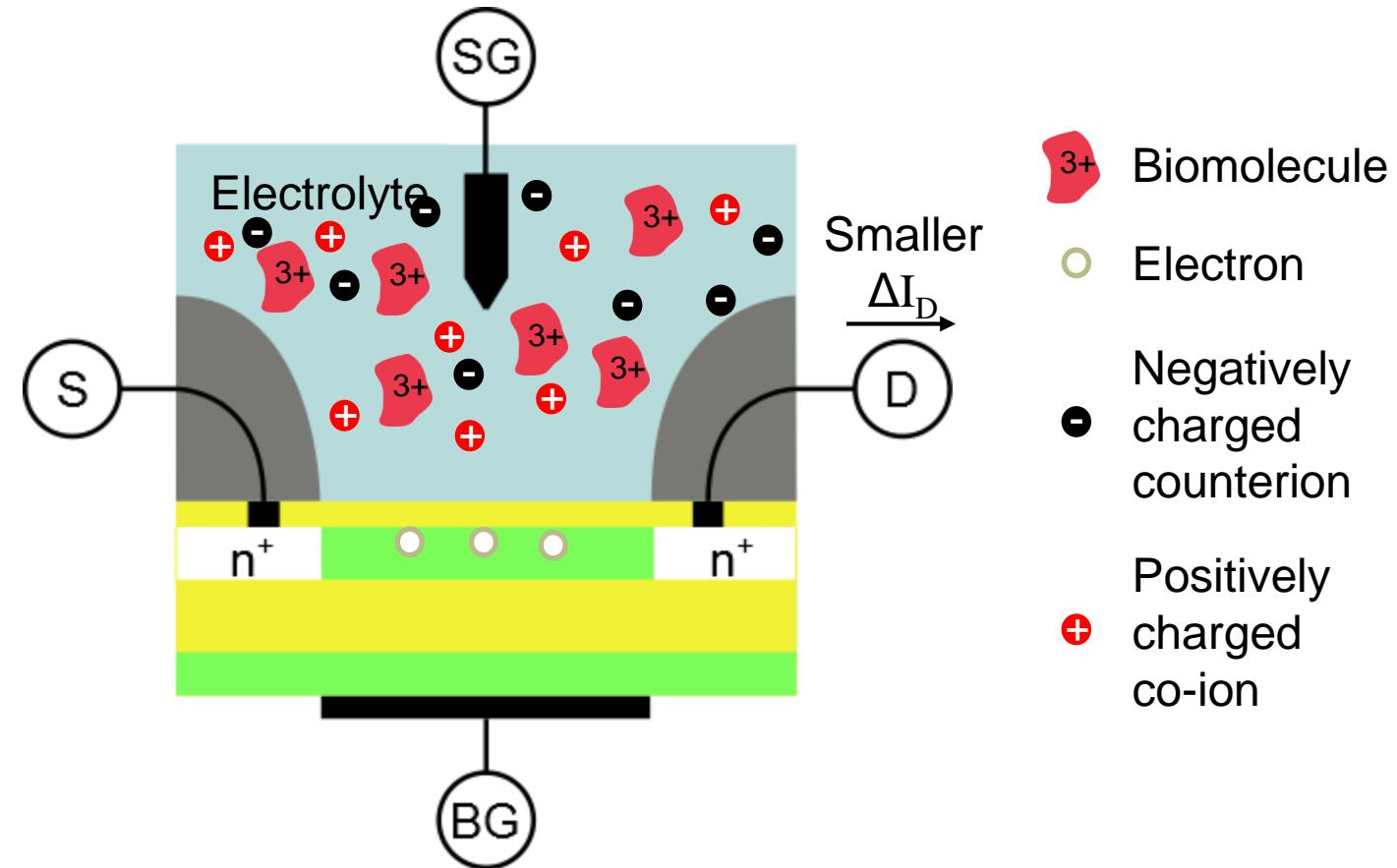
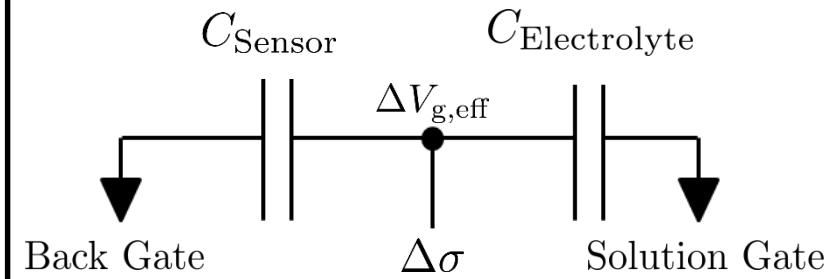
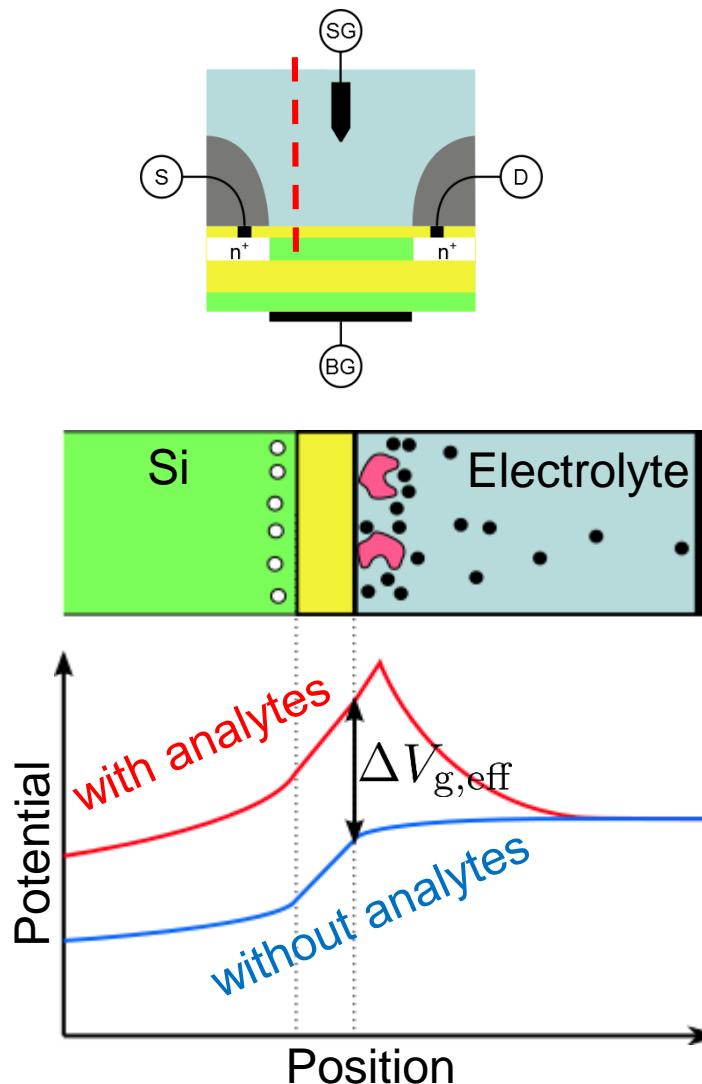


Figure of Merit: $\Delta I / I_0$

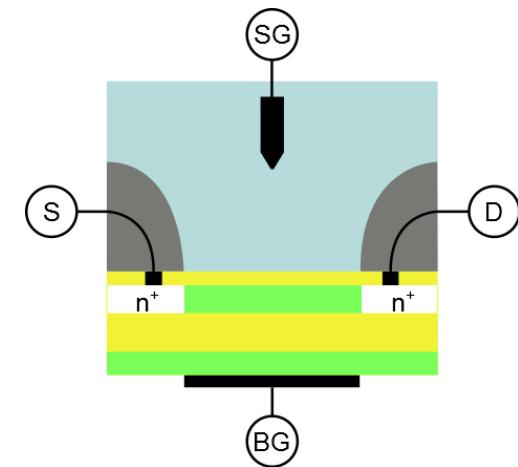
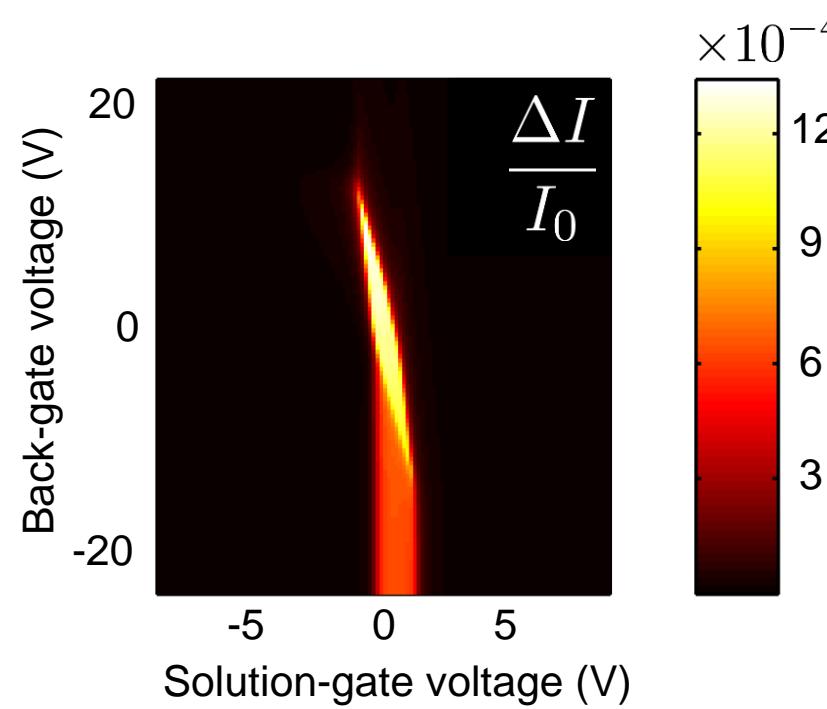


$$\frac{\Delta I}{I_0} = \Delta\sigma \frac{d(\Delta V_{g,\text{eff}})}{d(\Delta\sigma)} \frac{\frac{d(\Delta I)}{d(\Delta V_{g,\text{eff}})}}{I_0}$$

$$\frac{\frac{d(\Delta I)}{d(\Delta V_{g,\text{eff}})}}{I_0} = \frac{g_m}{I_D}$$

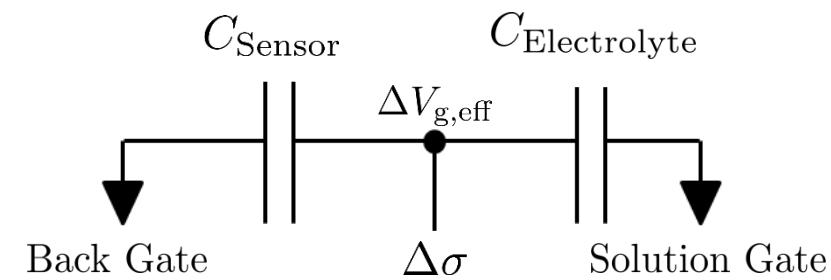
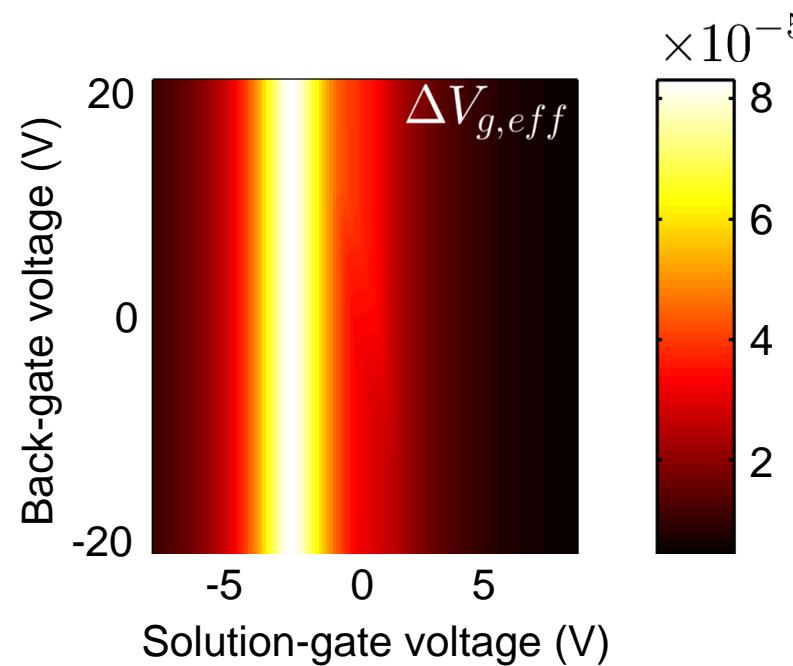
Sensitivity is a Function of Biasing Point

$$\frac{\Delta I}{I_0} = \Delta\sigma \frac{d(\Delta V_{g,\text{eff}})}{d(\Delta\sigma)} \frac{\frac{d(\Delta I)}{d(\Delta V_{g,\text{eff}})}}{I_0}$$



Bias Dependence of $\Delta V_{g,\text{eff}}$

$$\frac{\Delta I}{I_0} = \Delta\sigma \frac{d(\Delta V_{g,\text{eff}})}{d(\Delta\sigma)} \frac{\frac{d(\Delta I)}{d(\Delta V_{g,\text{eff}})}}{I_0}$$



$$\Delta V_{g,\text{eff}} = \frac{\Delta\sigma}{C_{\text{Electrolyte}} + C_{\text{Sensor}}}$$

Electrolyte Capacitance is Dominant

- **Capacitance in Solution:**

- Solution with 100mM ionic strength:

$$C_{\text{Electrolyte}} = \frac{80\epsilon_0}{\lambda_{\text{Debye}}} = \frac{80\epsilon_0}{1\text{nm}} \quad \lambda_{\text{Debye}} \equiv \sqrt{\frac{\epsilon_w \epsilon_0 kT}{q^2 (c_+ + c_-)}}$$

$$\approx 70 \frac{\mu\text{F}}{\text{cm}^2}$$

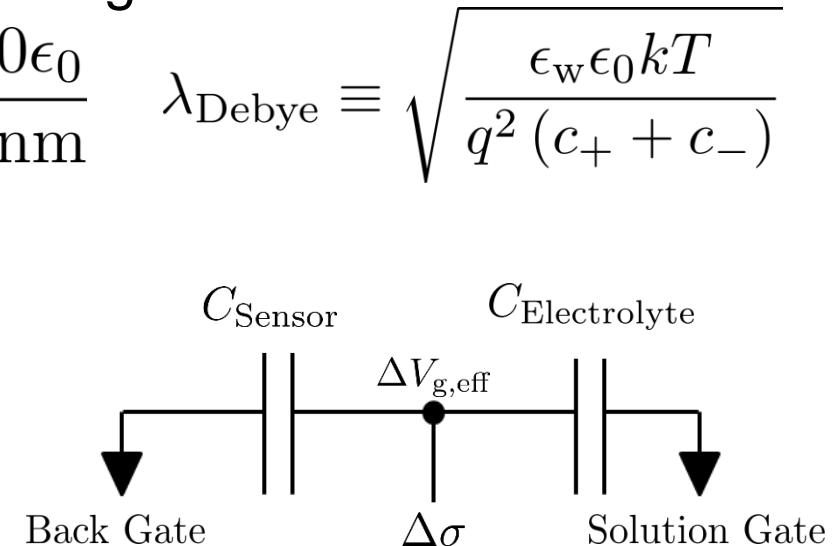
- **Capacitances in Sensor**

- 20nm SOI Layer:

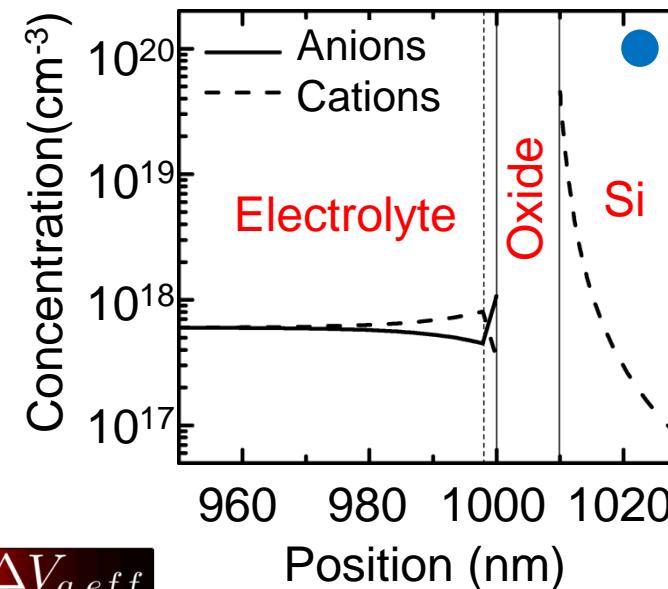
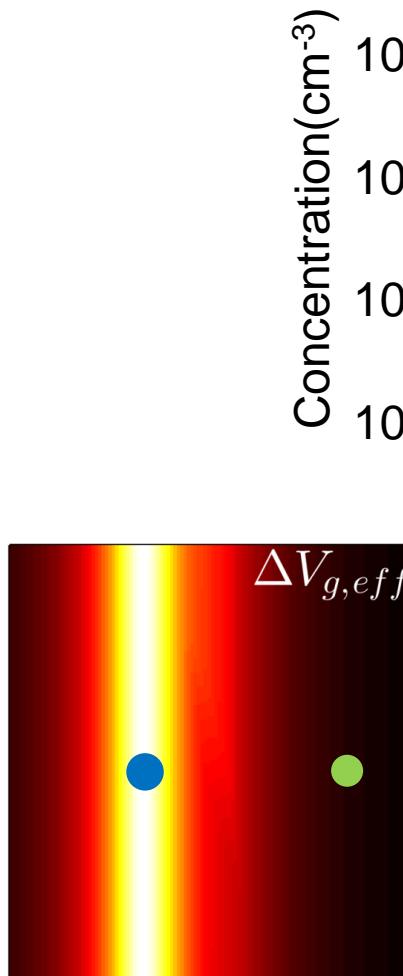
$$C_{\text{Si}} = \frac{11.7\epsilon_0}{20\text{nm}} \approx 0.5 \frac{\mu\text{F}}{\text{cm}^2}$$

- 1nm Native Oxide on Silicon:

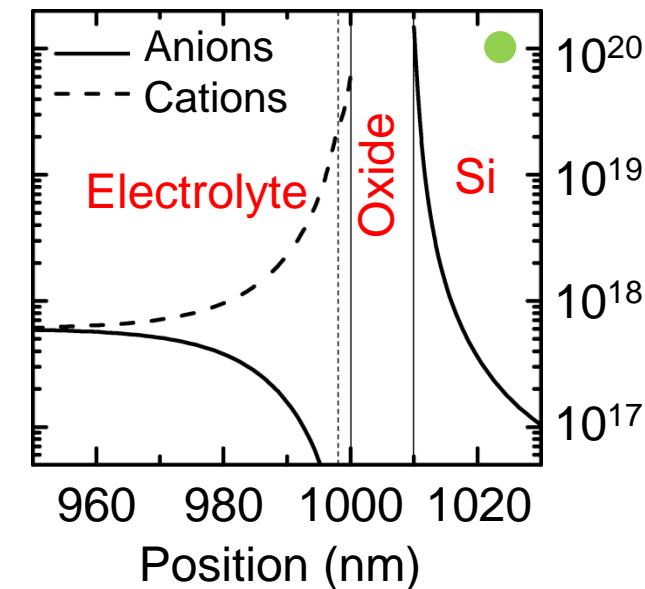
$$C_{\text{ox}} = \frac{3.9\epsilon_0}{1\text{nm}} \approx 3.5 \frac{\mu\text{F}}{\text{cm}^2}$$



Ion Concentration and $\Delta V_{g,\text{eff}}$



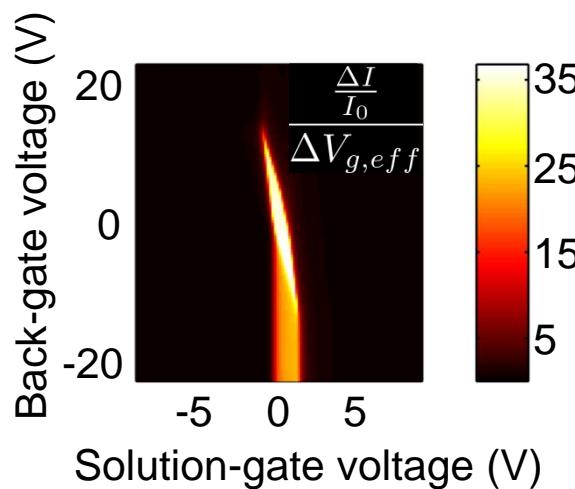
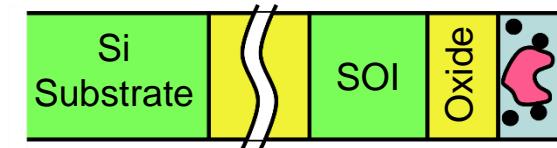
Biased where $\Delta V_{g,\text{eff}}$ peaks,
 $\Delta V_{g,\text{eff}} = 80 \mu\text{V}$



Biased in strong accumulation,
 $\Delta V_{g,\text{eff}} = 8 \mu\text{V}$

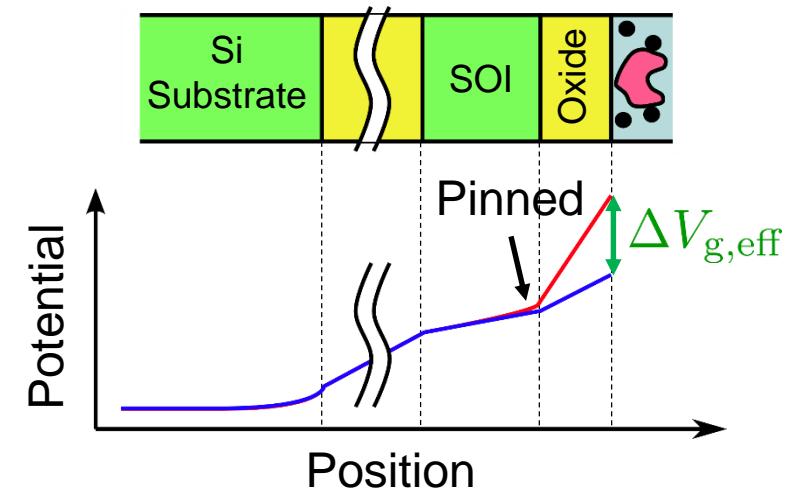
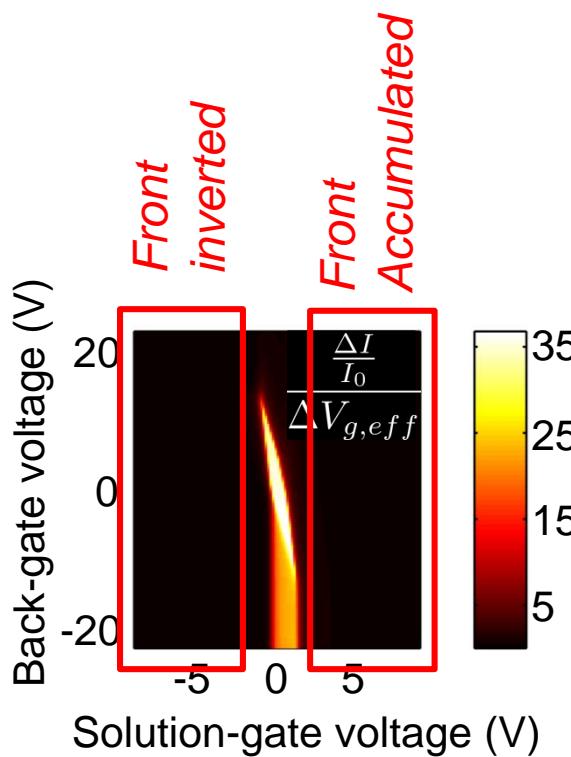
Optimizing FET Action

$$\frac{\Delta I}{I_0} = \Delta\sigma \frac{d(\Delta V_{g,\text{eff}})}{d(\Delta\sigma)} \frac{\frac{d(\Delta I)}{d(\Delta V_{g,\text{eff}})}}{I_0}$$



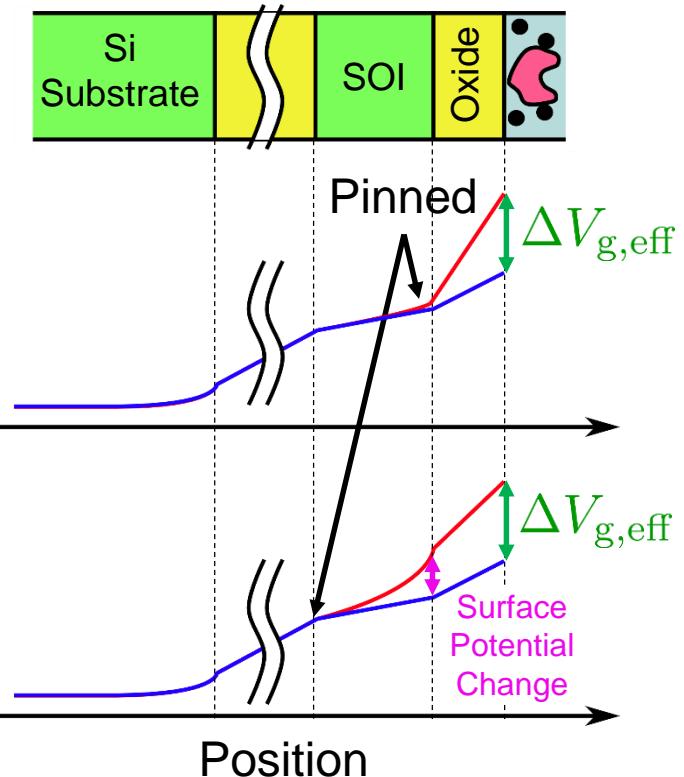
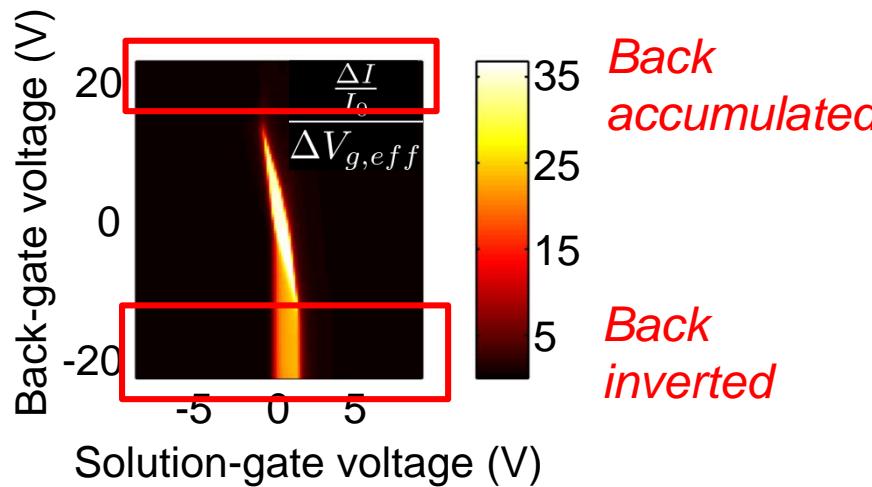
Optimizing FET Action

$$\frac{\Delta I}{I_0} = \Delta\sigma \frac{d(\Delta V_{g,\text{eff}})}{d(\Delta\sigma)} \frac{\frac{d(\Delta I)}{d(\Delta V_{g,\text{eff}})}}{I_0}$$



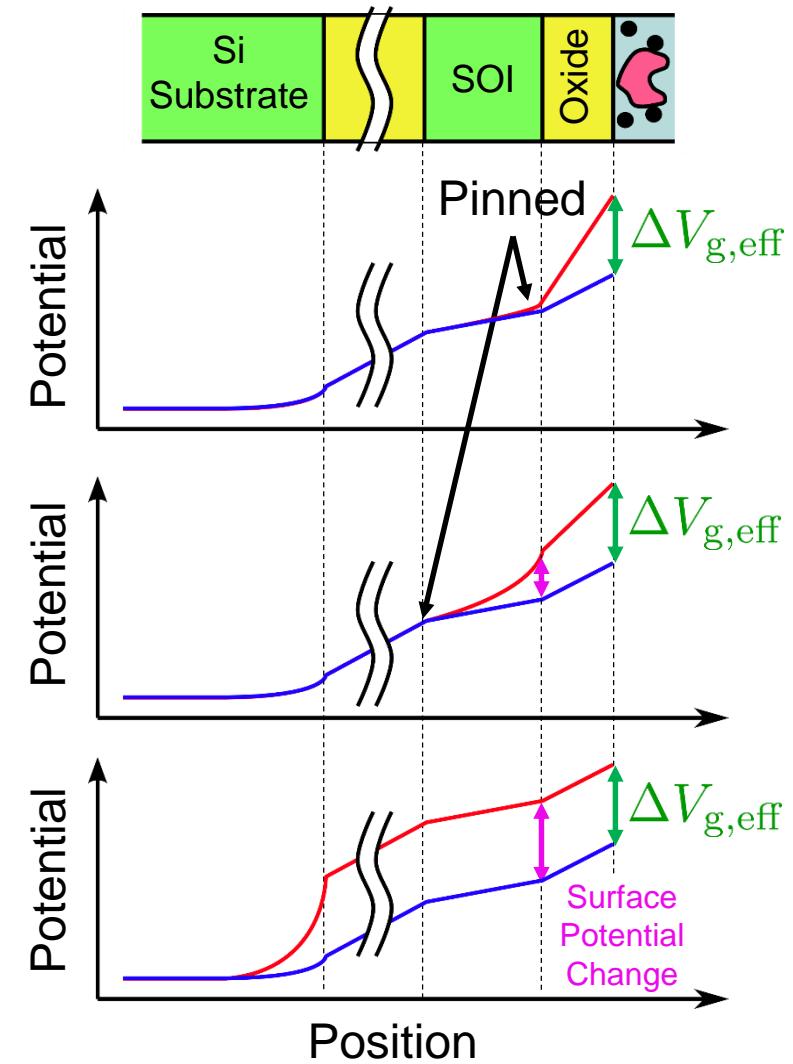
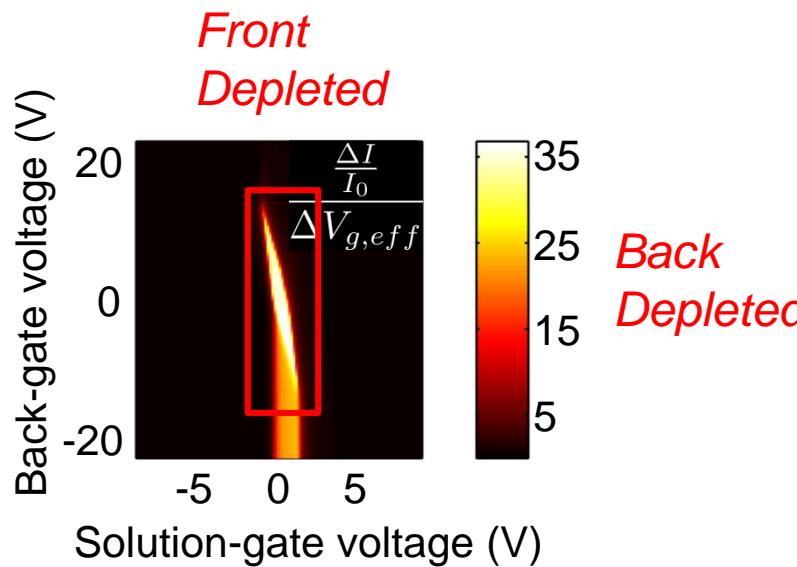
Optimizing FET Action

$$\frac{\Delta I}{I_0} = \Delta\sigma \frac{d(\Delta V_{g,\text{eff}})}{d(\Delta\sigma)} \frac{\frac{d(\Delta I)}{d(\Delta V_{g,\text{eff}})}}{I_0}$$

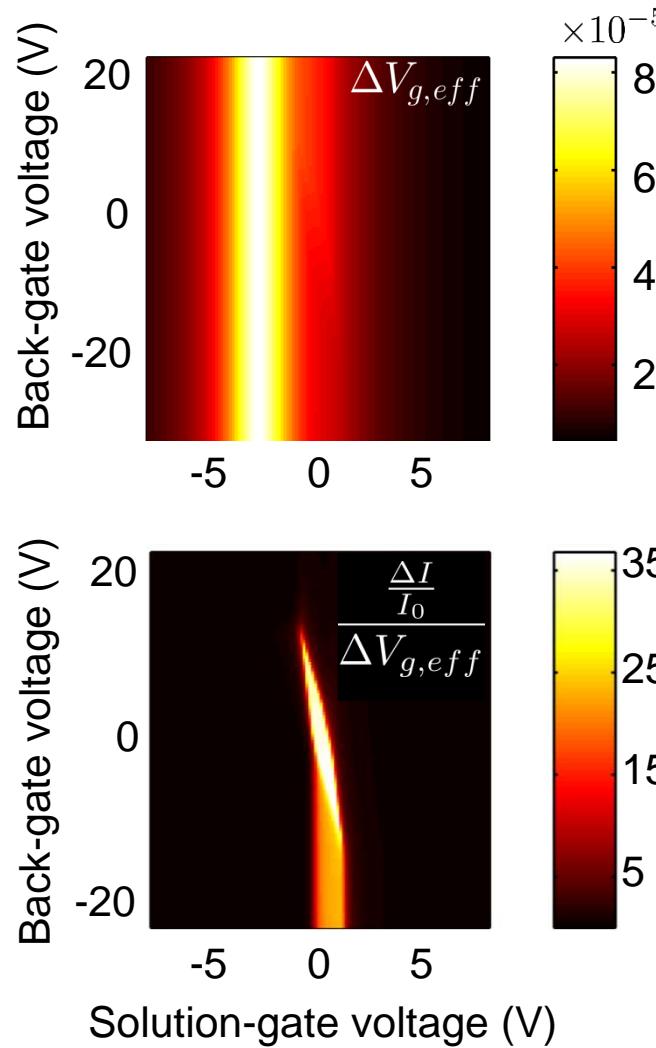


Optimizing FET Action

$$\frac{\Delta I}{I_0} = \Delta\sigma \frac{d(\Delta V_{g,\text{eff}})}{d(\Delta\sigma)} \frac{\frac{d(\Delta I)}{d(\Delta V_{g,\text{eff}})}}{I_0}$$

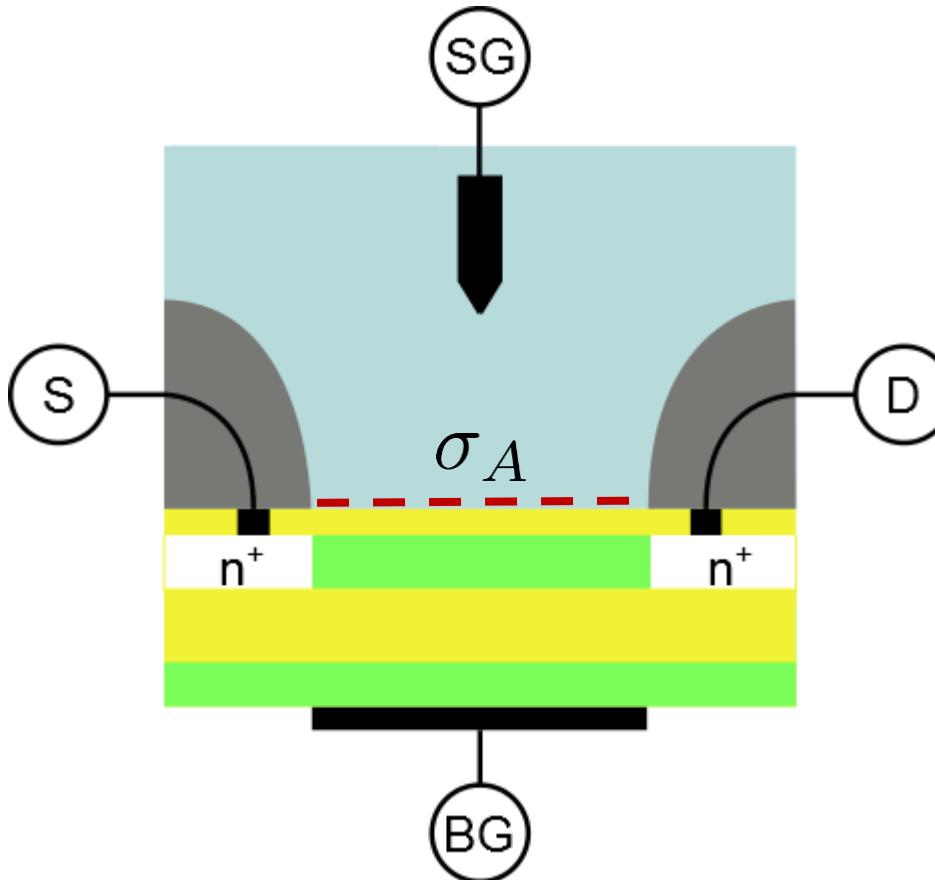


Maxima Do Not Coincide



$$\frac{\Delta I}{I_0} = \Delta\sigma \frac{d(\Delta V_{g,eff})}{d(\Delta\sigma)} \frac{\frac{d(\Delta I)}{d(\Delta V_{g,eff})}}{I_0}$$

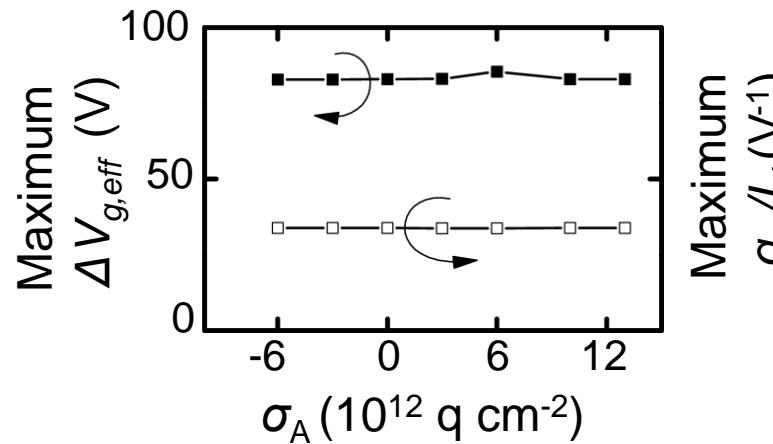
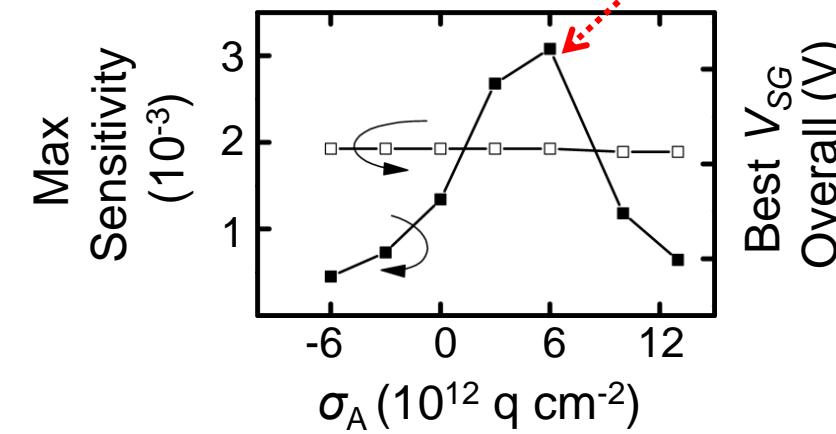
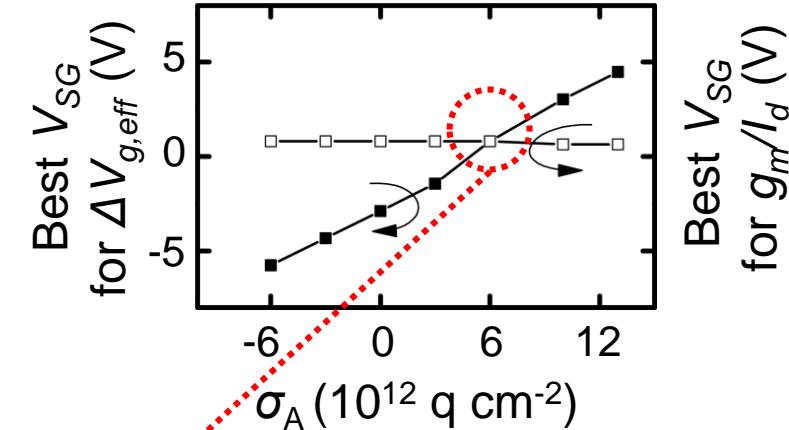
Adding “Adjustment Charges”



Adjustment charges could come from:

- Charged surface groups
- Dipoles between surface layers
- Charged receptors
- Charged linkers

Varying Adjustment Charge Density σ_A

Maximum $g_m/I_d (\text{V}^{-1})$ Best V_{SG} Overall (V)



Conclusions

- Biasing matters (a lot!)
 - Bias in region of steepest slope
 - Screening matters
 - Minimize surface electric field
 - Surface charge engineering can help
-
- Shoorideh, K., Chui, C.O., *Electron Devices, IEEE Transactions on*, vol.59, no.11, pp. 3104-3110, Nov. 2012



Thank You For Your Attention

Questions?